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priority Filing Date August 20, 2001
Inventor Chen et al.
Assignee Micron Technology, Inc.
priority Group Art Unit 2813
priority Examiner Huynh, Y.
Attorney's Docket No. MI22-1927
Title: Methods of Forming a Capacitor Structure (As Amended)

PRELIMINARY AMENDMENT

To: Box Patent Application
Assistant Commissioner for Patents
Washington, D.C. 20231

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AMENDMENTS

In the Specification

Please replace the title with the following:

--Methods of Forming a Capacitor Structure--.

At Page 1, before the "Technical Field" section, please insert:

--CROSS REFERENCE TO RELATED APPLICATION

9' This patent resulted from a divisional application of U.S. Patent Application
Serial No. 09/933,913, which was filed on August 20, 2001.--.